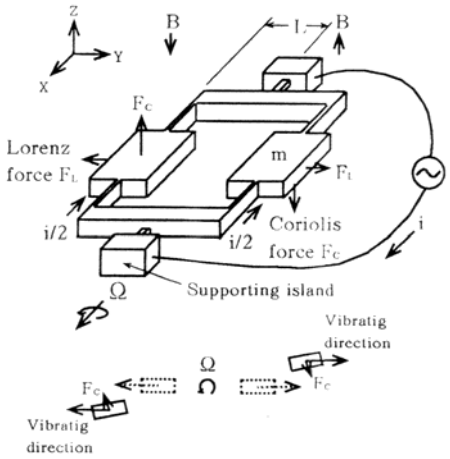
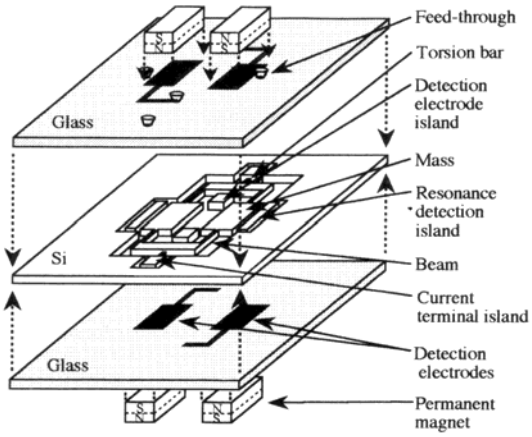
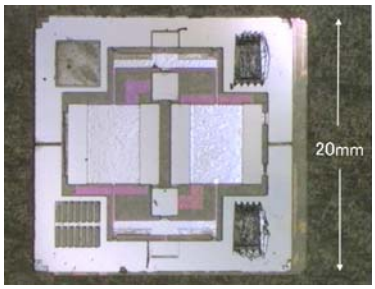
B1

Electromagnetically Driven Resonating Gyro

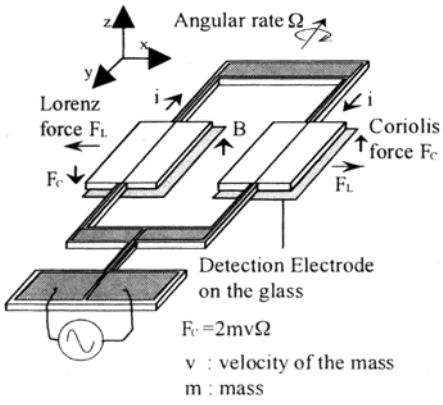


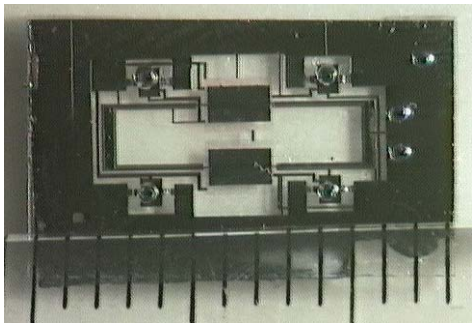


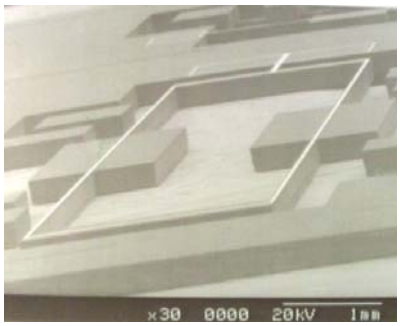


Electromagnetically excited capacitive sensing gyro by anisotropic etching of (110) Si (Tohoku Univ. – Toyota Motor)

Reference : M.Hashimoto, C.Cabuz, K.Minami and M.Esashi, Silicon Resonant Angular Rate Sensor Using Electromagnetic Exitation and Capacitive Detection, Micro System Technologies'94 (1994) pp.763-772

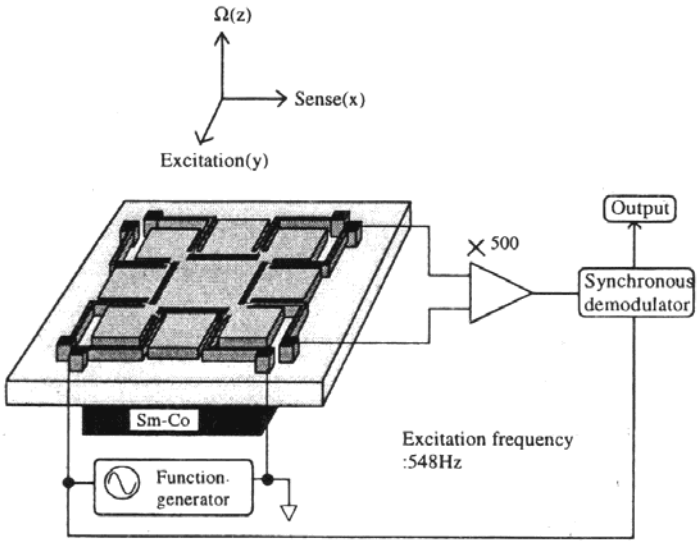


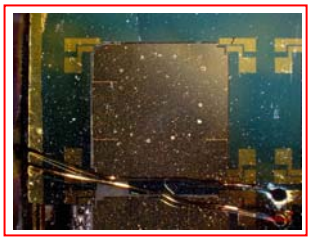


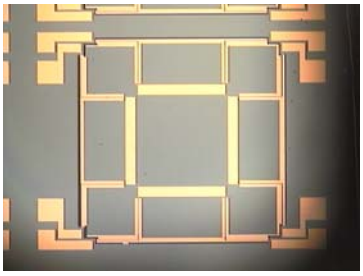


Electromagnetically excited capacitive sensing gyro by Deep RIE

Reference : J.Choi, K.Minami and M.Esashi : Application of Deep Reactive Ion Etching for Silicon Angular Rate Sensor, Microsystem Technologies, 2 (1996) pp.186-199







Electromagnetically excited and electromotive voltage sensing resonating gyro for Z-axis

Reference : J.-J. Choi, K.Minami, M.Esashi, Electromagnetical Excitation and Induced Electromotive Voltage Sensing Silicon Angular Rate Sensor, Trans. IEE of Japan, 118-E (1998) pp.641-646